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PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In Re the Application of:

JAHNS et al.

Serial No.: 10/658,984

Filed: September 10, 2003

Confirmation No.: 3965

Atty. File No.: 44500-00342

For: "INDUSTRIAL PROCESS FAULT
DETECTION USING PRINCIPAL
COMPONENT ANALYSIS"

) Group Art Unit: 2857

) Examiner: Not Yet Assigned

) INFORMATION DISCLOSURE STATEMENT

<p style="text-align: center;">CERTIFICATE OF MAILING</p> <p>I HEREBY CERTIFY THAT THIS CORRESPONDENCE IS BEING DEPOSITED WITH THE UNITED STATES POSTAL SERVICE AS FIRST CLASS MAIL IN AN ENVELOPE ADDRESSED TO COMMISSIONER FOR PATENTS, P.O. BOX 1450, ALEXANDRIA, VA 22313-1450 ON <u>5/14/04</u></p> <p style="text-align: center;">MARSH FISCHMANN & BREYFOGLE LLP</p> <p>BY: <u>[Signature]</u> DAXMARA SANCHEZ</p>

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

Pursuant to Applicant's duty of disclosure under 37 CFR § 1.56 and 37 CFR §§ 1.97-1.98, Applicant hereby submits the enclosed PTO Form 1449, although Applicant does not admit that any of such documents, alone or in any combination, is considered to be material to patentability as defined in 37 CFR § 1.56(b). Moreover, the inclusion of these documents is not to be construed as an admission by Applicant that each such document is prior art as to the above-identified application.

Pursuant to the Official Gazette Notice of August 5, 2003, copies of any U.S. Patents or published U.S. Patent Applications are not being submitted herewith. Copies of any foreign patent and non-patent documents are submitted herewith.

Attorney Docket No.: 44500-00342

PATENT APPLICATION

Respectfully submitted,

MARSH FISCHMANN & BREYFOGLE LLP

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Date: May 14, 2004

INFORMATION DISCLOSURE CITATION

(Use several sheets if necessary)

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ATTY DOCKET NO.

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GROUP

2857

U.S. PATENT DOCUMENTS

*EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
	1.	5,658,423	08/19/97	ANGELL ET AL.	438	9	
	2.	5,864,773	01/26/99	BARNA ET AL.	702	85	
	3.	6,153,115	11/28/00	LE ET AL.	216	60	
	4.	6,192,826	02/27/01	SMITH, JR. ET AL.	118	723	
	5.	6,419,846	07/16/02	TOPRAC ET AL.	216	60	
	6.	6,442,445	08/27/02	BUNKOFSKE ET AL.	700	108	
	7.	6,521,080	02/18/03	BALASUBRAMHANYA	156	345.24	
	8.	2002/0104832	08/08/02	TANAKA ET AL.	219	121.41	
	9.	2002/0119668	08/29/02	BELL	438	707	
	10.	2003/0055523	03/20/03	BUNKOFSKE ET AL.	700	108	

FOREIGN PATENT DOCUMENTS

		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
							YES	NO

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

	A.	Infineon Technologies, "USING MULTI WAY PCA (MPCA) FOR ADVANCED MONITORING AND DIAGNOSIS FOR PLASMA PROCESSING BASED ON OPTICAL EMISSION SPECTROSCOPY" by Zimpel et al., SEMATECH AEC/APC Symposium XII, (Sept. 24-28, 2000)
	B.	Infineon Technologies, "SUPERVISION OF PLASMA PROCESSES USING MULTI-WAY PRINCIPAL COMPONENT ANALYSIS" by Knobloch et al, IVC-15 Int'l Symposium. (Oct. 02-06, 2000)

EXAMINER

DATE CONSIDERED

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
							YES	NO

OTHER DOCUMENTS *(Including Author, Title, Date, Pertinent Pages, Etc.)*

		C.	Eigenvector Research, Inc., "DEVELOPMENT AND BENCHMARKING OF MULTIVARIATE STATISTICAL PROCESS CONTROL TOOLS FOR A SEMICONDUCTOR ETCH PROCESS: IMPROVING ROBUSTNESS THROUGH MODEL UPDATING" by Gallagher et al. (1997)

EXAMINER

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